

Notice of References Cited		Application/Control No. 10/522,533	Applicant(s)/Patent Under Reexamination MESCHKE, FRANK	
		Examiner ELIZABETH A. BURKHART	Art Unit 1792	Page 1 of 1

U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
*	A	US-6,579,833	06-2003	McNallan et al.	508/100
	B	US-			
	C	US-			
	D	US-			
	E	US-			
	F	US-			
	G	US-			
	H	US-			
	I	US-			
	J	US-			
	K	US-			
	L	US-			
	M	US-			

FOREIGN PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N					
	O					
	P					
	Q					
	R					
	S					
	T					

NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Matsui et al, Three-dimensional nanostructure fabrication by focused-ion-beam chemical vapor deposition, J. Vac. Sci. Technol. B 18(6), Nov/Dec 2000, p. 3181-3184.
	V	Kusunoki et al, Aligned carbon nanotube film self-organized on a SiC wafer, Jpn. J. Appl. Phys. Vol. 37 (1998), p. L605-L606.
	W	
	X	

*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.